IN THE SPECIFICATION:

Please amend the paragraph beginning on Page 7, line 14 to line 18 to read as follows:

--For this the patterned layer of the stamp device provides a force transducer, which may be any device or sensor, as known in the art, for force or pressure measurement in at least one force transducer zone for monitoring the normal force induced pressure on the stamp device acting between said stamp and said substrate. The force transducer zone serves as a force detector having a defined patterned structure surrounding at least an area free of unencumbered by pattern structures and in said unencumbered area free of structures additional structures are provided which narrow the unencumbered area free of structures in at least one direction.--

Please amend the paragraph beginning on page 15, line 4 to line 8 to read as follows:

--A force transducer zone for monitoring lateral or shear forces as shown in figure 3D. The structure on the upper half with the narrow bridge at the right that becomes larger towards the left side is to detect the stability of the stamp device against squeezing of small structures and shear forces during printing perpendicular to this narrow bridge. A shear force will induce a lateral displacement of the line from its original symmetry axis. A somewhat differently patterned zone is evident from figure 3E.--

Please amend the paragraph beginning on page 15, line 10 to line 12 to read as follows:

--Figure 3F shows the arrangement of force transducer zones 9 at the margin of a square shaped stamp device from the bottom view. In the center region of the stamp device patterned structures 3 are located (not shown). A force transducer (not shown) may comprise

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measuring one or more sensors which measure the force exerted by the stamp device against the substrate, from which there can then be derived the pressure exerted by the stamp in the transducer zones.--

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